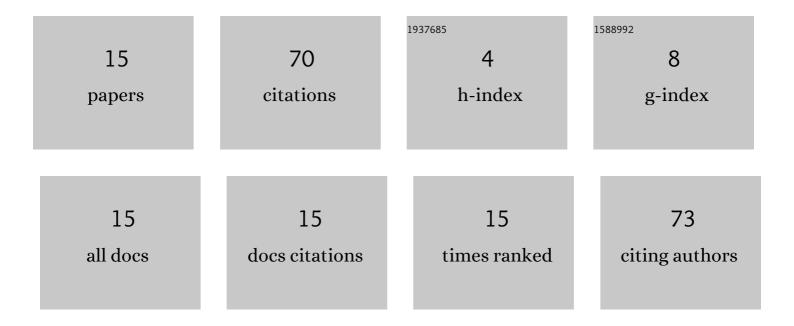
Tien Hsi Lee

List of Publications by Year in descending order

Source: https://exaly.com/author-pdf/3589604/publications.pdf Version: 2024-02-01



TIEN HOLLEE

#	Article	IF	CITATIONS
1	Low-temperature rough-surface wafer bonding with aluminum nitride ceramics implemented by capillary and oxidation actions. Ceramics International, 2022, 48, 8766-8772.	4.8	1
2	Low-Temperature Rough-Surface Wafer Bonding with AlN/AlN Via Oxygen Plasma Activation. ECS Transactions, 2022, 108, 49-50.	0.5	0
3	Low-Temperature Rough-Surface Wafer Bonding with AlN/AlN Via Oxygen Plasma Activation. ECS Meeting Abstracts, 2022, MA2022-01, 1046-1046.	0.0	0
4	Utilization of Low Wavelength Laser Linking with Electrochemical Etching to Produce Nano-Scale Porous Layer on p-Type Silicon Wafer with High Luminous Flux. ECS Journal of Solid State Science and Technology, 2021, 10, 016003.	1.8	0
5	Self-Powered, Hybrid, Multifunctional Sensor for a Human Biomechanical Monitoring Device. Applied Sciences (Switzerland), 2021, 11, 519.	2.5	5
6	Forming a Photoluminescent Layer on Another Surface in the Dark through Lasering of N-Type Silicon in an Electrolyte. ACS Omega, 2020, 5, 26497-26503.	3.5	3
7	Annihilating Pores in the Desired Layer of a Porous Silicon Bilayer with Different Porosities for Layer Transfer. Scientific Reports, 2019, 9, 12631.	3.3	12
8	Communication—Effect of Free-Carrier Absorption on an Anodized Silicon Surface for Producing Dense and Uniform Nanocrystals. Journal of the Electrochemical Society, 2018, 165, H99-H101.	2.9	2
9	Rapid Fabrication of 100 nm or Thinner Fully Depleted Silicon-on-Insulator Materials for Ultralow Energy Consumption. ACS Applied Nano Materials, 2018, 1, 2414-2420.	5.0	2
10	Near-Field Electrospun Piezoelectric Fibers as Sound-Sensing Elements. Polymers, 2018, 10, 692.	4.5	28
11	Communication—Eliminating Thickness Measurement Uncertainty of Capacitive Displacement Sensor in High Resistivity Substrate by Photoconduction. ECS Journal of Solid State Science and Technology, 2017, 6, P323-P325.	1.8	0
12	Nanoscale Layer Transfer by Hydrogen Ion-Cut Processing: A Brief Review Through Recent U.S. Patents. Recent Patents on Nanotechnology, 2017, 11, 42-49.	1.3	3
13	Inhibition Effect of a Laser on Thickness Increase of p-Type Porous Silicon in Electrochemical Anodizing. Journal of the Electrochemical Society, 2016, 163, H265-H268.	2.9	11
14	Sharpening Si Nanocrystals on the Bulk Surface by Nanoscale Electrochemistry through Controlling the Hole Current with the Irradiation of Near-Infrared Laser. Journal of the Electrochemical Society, 2016, 163, E258-E262.	2.9	3
15	Thermal Stress Induced Thin Film Transfer from Single-crystal Silicon Layer on Sapphire Substrate. Integrated Ferroelectrics, 2013, 144, 73-78.	0.7	0